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<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> (Use as many sheets as necessary)		<b>Complete if Known</b>	
		Application Number	10/827,252
		Filing Date	April 20, 2004
		First Named Inventor	Mohiuddin Mala
		Art Unit	2873
		Examiner Name	William C. Choi
Attorney Docket Number	14682		
Sheet 2	of 2		

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, pages), volume-issue number(s), publisher, city and /or country where published.	T <sup>2</sup>
WC	AH	Johanna I. Young, et al.; COMPARATIVE STUDY OF 2-DOF MICROMIRRORS FOR PRECISION LIGHT MANIPULATION; SPIE Smart Structures and Materials Conference, Newport Beach, CA, March 4-7, 2001.	<input type="checkbox"/>
	AI	Veljko Milanovic, et al.; MONOLITHIC HIGH ASPECT RATIO TWO-AXIS OPTICAL SCANNERS IN SOI; 2003 MEMS Conference, Kyoto, Japan, January 19-23, 2003, pp. 255-258.	<input type="checkbox"/>
	AJ	Sunghoon Kwon, et al.; LARGE-DISPLACEMENT VERTICAL MICROLENS SCANNER WITH LOW DRIVING VOLTAGE; IEEE Photonics Technology Letters, Vol. 14, No. 11, November 2002, pp. 1572-1574.	<input type="checkbox"/>
	AK	D.A. Horsley et al.; MULTI-DEGREE OF FREEDOM DYNAMIC CHARACTERIZATION OF DEEP-ETCHED SILICON SUSPENSIONS; Solid State Sensor and Actuator Workshop, Hilton Head, June 4-8, 2000, pp 81-84.	<input type="checkbox"/>
	AL	B.M. Evans et al.; FINITE ELEMENT MODELING OF MICROMACHINED MEMS PHOTON DEVICES; Miniaturized Systems with Micro-optics and MEMS, Santa Clara, September 1999, SPIE 3878, pp 253-260.	<input type="checkbox"/>
↓	AM	David Burns, et al.; OPTICAL BEAM STEERING USING SURFACE MICROMACHINED GRATINGS AND OPTICAL PHASED ARRAYS; Optical Scanning Systems: Design and Application, San Diego, CA, July 1997, SPIE 3131, pp. 99-110.	<input type="checkbox"/>
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Examiner Signature	/William Choi/	Date Considered	06/23/2006
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